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(12) **United States Design Patent** (10) **Patent No.:** **US D826,185 S**
Kosugi et al. (45) **Date of Patent:** **** Aug. 21, 2018**

(54) **CEILING HEATER FOR SUBSTRATE PROCESSING APPARATUS**

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(**) Term: **15 Years**

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(30) **Foreign Application Priority Data**

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(51) **LOC (11) Cl.** **13-03**

(52) **U.S. Cl.**
USPC **D13/182**

(58) **Field of Classification Search**
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D15/140, 144.1
CPC H01L 21/67011; H01L 21/67098; H01L
21/67103; H01L 21/67109; H01L
21/67115

See application file for complete search history.

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(Continued)

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(57) **CLAIM**

We claim the ornamental design for a ceiling heater for substrate processing apparatus, as shown and described.

DESCRIPTION

FIG. 1 is a front, bottom and right side perspective view of a ceiling heater for substrate processing apparatus showing our new design;

FIG. 2 is a front elevational view thereof;

FIG. 3 is a left side elevational view thereof;

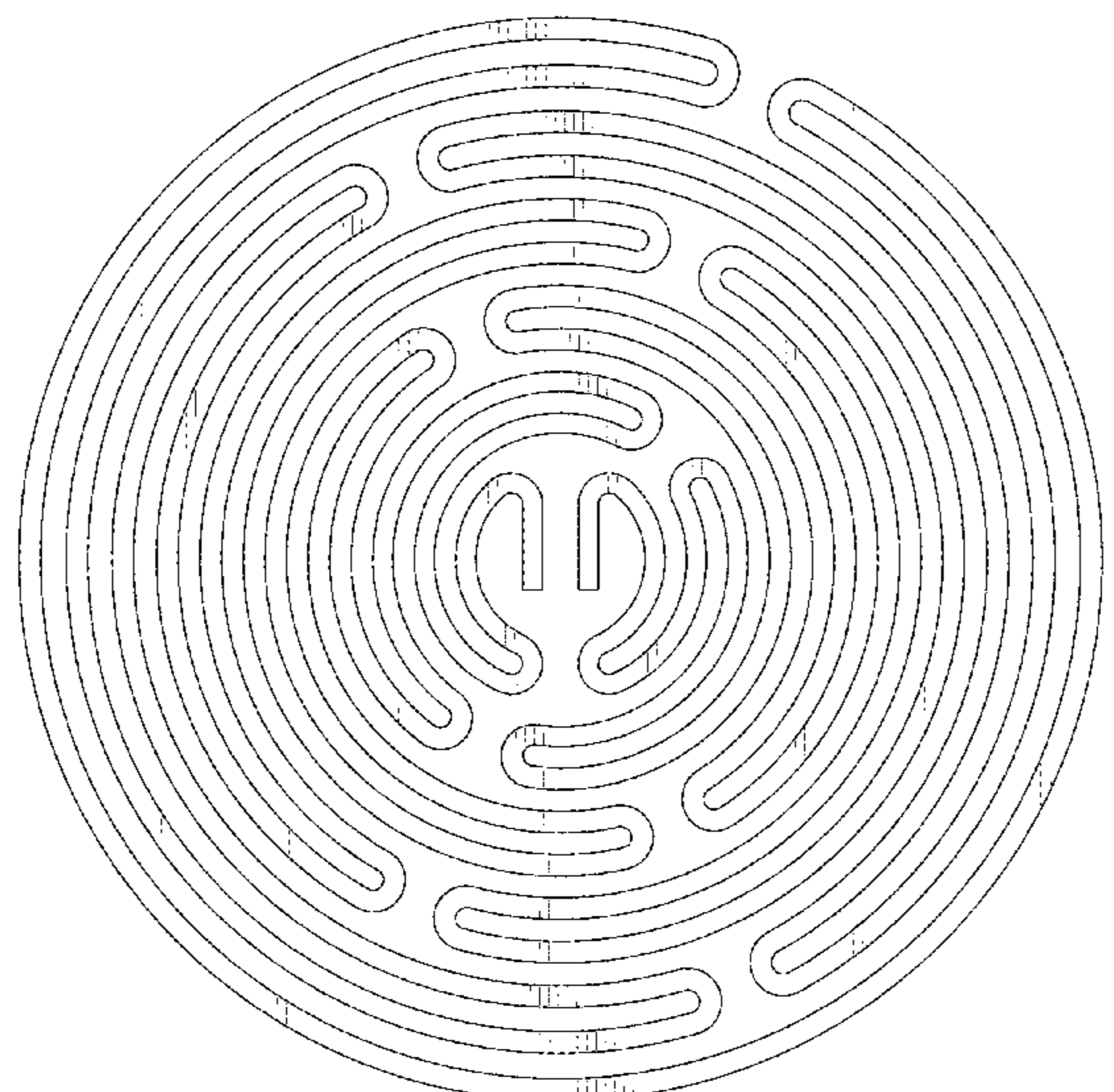
FIG. 4 is a right side elevational view thereof;

FIG. 5 is a top plan view thereof;

FIG. 6 is a bottom plan view thereof; and,

FIG. 7 is a rear elevational view thereof.

1 Claim, 4 Drawing Sheets



(56)

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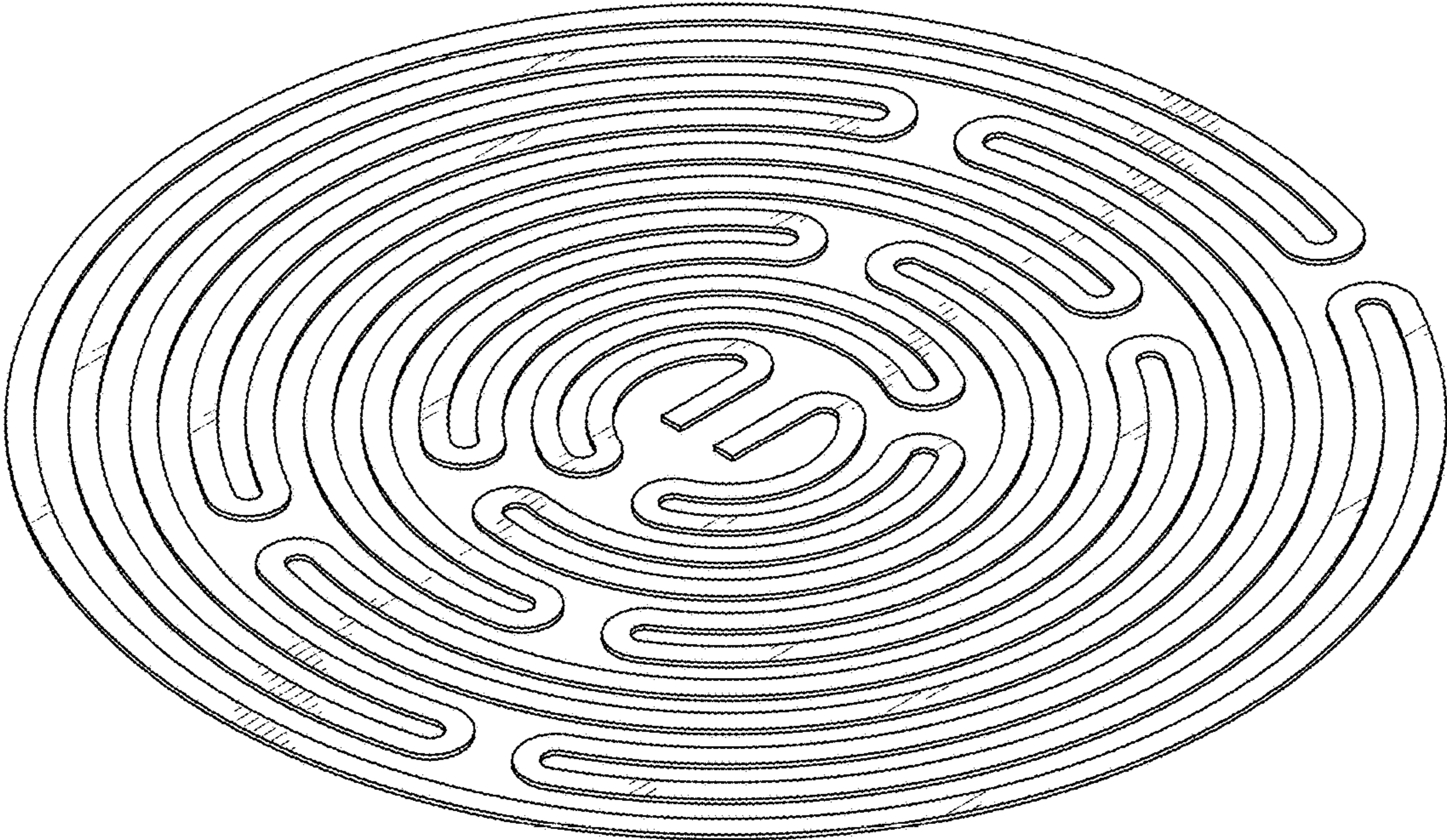


FIG. 1

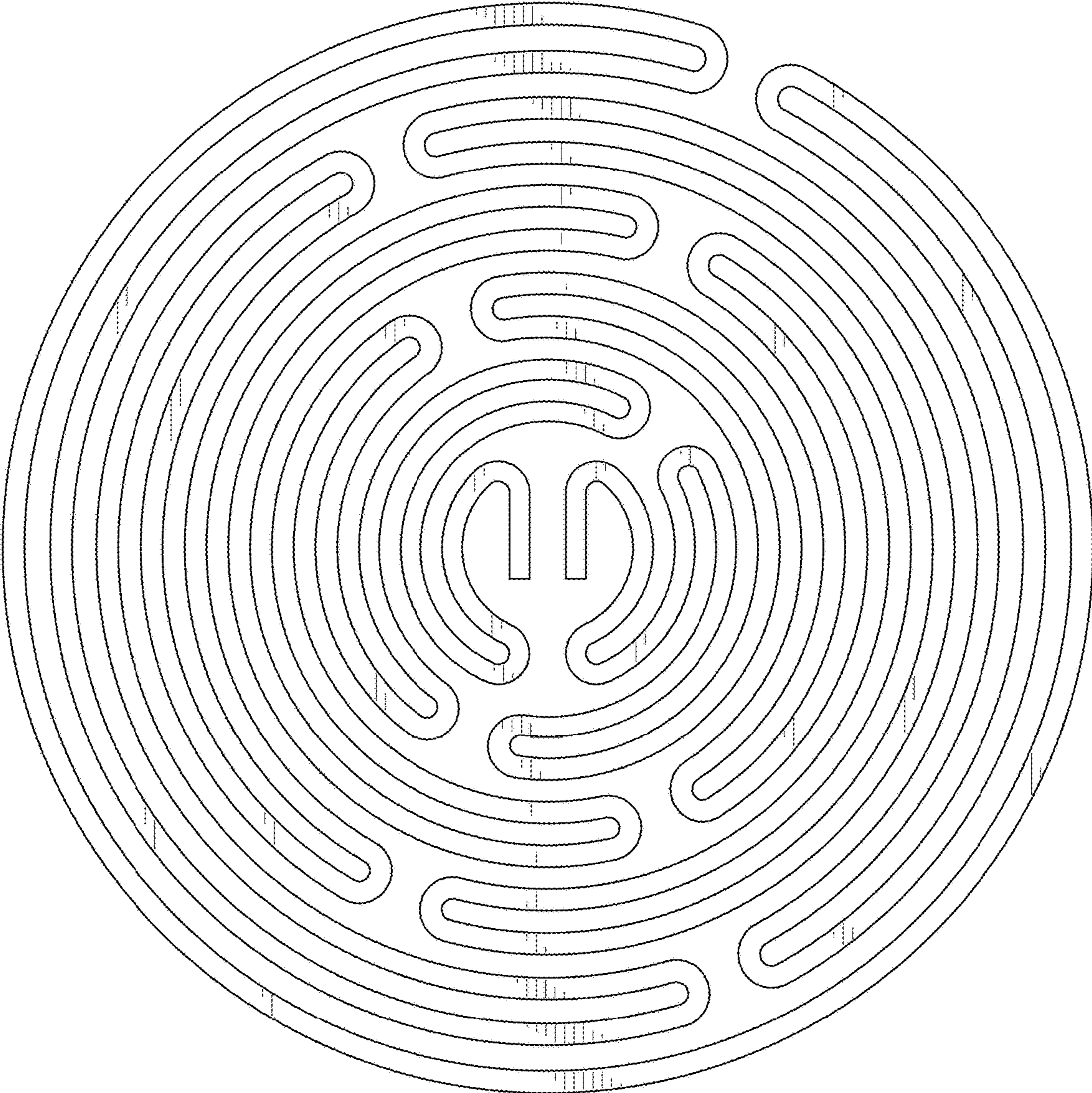


FIG. 2



FIG. 3

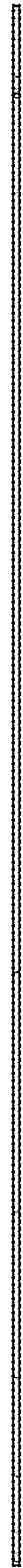


FIG. 4

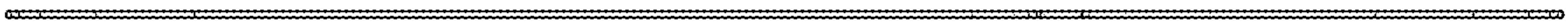


FIG. 5

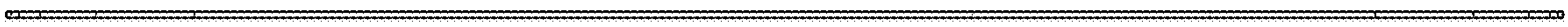


FIG. 6

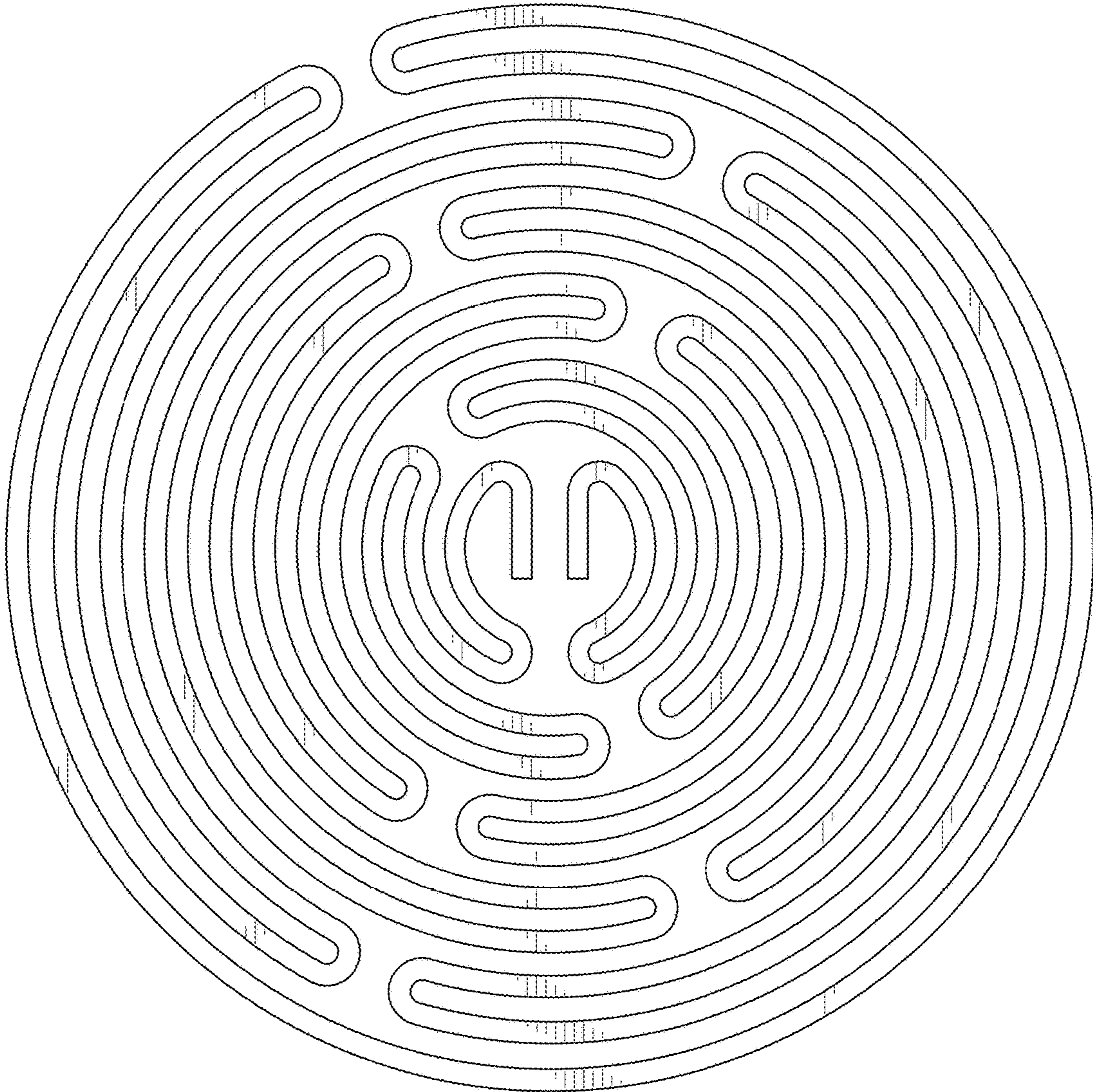


FIG. 7